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CONFIRMATION NO. 1783

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|--|---|---|---|--|--------------------------------|
| SERIAL NUMBER 10/532,459 | FILING OR 371(c) DATE 11/02/2005 RULE | CLASS 438 | GROUP ART UNIT 2812 | ATTORNEY DOCKET NO. AB-1432 US | |
| APPLICANTS Hyun-Jae Kim, Seongnam-city, KOREA, REPUBLIC OF; Myung-Koo Kang, Seoul, KOREA, REPUBLIC OF; | | | | | |
| ** CONTINUING DATA ***** <i>NA</i> This application is a 371 of PCT/KR03/02212 10/21/2003 | | | | | |
| ** FOREIGN APPLICATIONS ***** REPUBLIC OF KOREA 10-2002-0064511 10/22/2002 <i>NA</i> | | | | | |
| Foreign Priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 (a-d) conditions met <input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance Verified and Acknowledged <i>[Signature]</i> Examiner's Signature Initials | | STATE OR COUNTRY KOREA, REPUBLIC OF | SHEETS DRAWING 5 | TOTAL CLAIMS 7 | INDEPENDENT CLAIMS 3 |
| ADDRESS 32605 | | | | | |
| TITLE Method of polycrystallization, method of manufacturing polysilicon thin film transistor, and laser irradiation device therefor | | | | | |
| FILING FEE RECEIVED 1030 | FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following: | | <input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit | | |